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Cont
the EMI shield member having a contact wall defining the aperture, the aperture defining contact wall being in contact with the contact protuberance received in the aperture;

the contact protuberance being dimensioned such that the contact protuberance supports the EMI shield member.

REMARKS

Claims 1, 3, 4, 6-8, and 10-18 were rejected under 35 U.S.C. §102(b) as being anticipated by Mok et al., U.S. Patent No. 5,704,117. Claims 2, 5 and 9 were rejected under 35 U.S.C. §103(a) as being unpatentable over Mok et al.

Independent claims 1, 3, 10, 12, 15, and 18 provide that the contact protuberance is dimensioned such that it supports the EMI shield member. In contrast, what the Examiner deems to be the contact protuberance in Mok et al., element 32, does not support the EMI shield member in Mok et al. Element 32, is merely alignment pins passing through holes 26 in the shield 10 and aligning the shield 10, not supporting it (column 3, lines 53-66; Fig. 4).

Attached hereto is a marked-up version of the changes made to the specification and claims by the current amendment. The attached pages are captioned "**VERSION WITH MARKINGS TO SHOW CHANGES MADE.**"

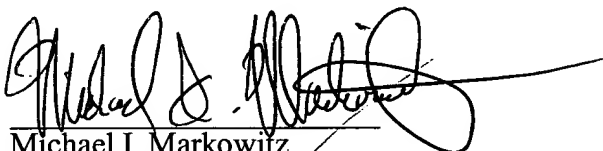
CLOSING

An earnest effort has been made to be fully responsive to the Examiner's objections. In view of the above amendments and remarks, it is believed that independent claims 1, 3, 10, 12, 15, and 18 are in condition for allowance, as well as those claims dependent therefrom. Passage of this case to allowance is earnestly solicited.

However, if for any reason the Examiner should consider this application not to be in condition for allowance, he is respectfully requested to telephone the undersigned attorney at the number listed below prior to issuing a further Action.

Any fee due with this paper, not fully covered by an enclosed check, may be charged on Deposit Account 50-1290.

Respectfully submitted,



Michael I. Markowitz
Reg. No. 30,659

Enclosure: Version With Markings to Show Changes Made

KATTEN MUCHIN ZAVIS ROSENMAN
575 MADISON AVENUE
NEW YORK, NEW YORK 10022
(212) 940-8687
DOCKET NO.:NECM 19.067
MIM:lh
CUSTOMER NO.: 026304

VERSION WITH MARKINGS TO SHOW CHANGES MADE

IN THE SPECIFICATION

The paragraphs on page 3, lines 12-25, have been rewritten as follows:

According to the EMI shielding structure shown in Figure 11, the vertex of each conical contact protuberance 111 and the EMI shield member 112 makes a point contact. Thus, an increased number of contact protuberances 111 are required to provide a sufficiently low resistance of the electrical connection between the EMI shield member 112 and the ground plane of the printed circuit [100.] 110.

In the EMI shielding structure shown in Figure 11, the thickness, as indicated at B, of the EMI shield member 112 adds to an elevation of the remote surface of the EMI shield member 112 from the printed circuit 110. If each contact protuberance 111 has the height A, the final elevation of the [remove] remote surface of the EMI shield member 112 can be expressed as the sum (A + B).

The table on page 7, lines 9-11, has been rewritten as follows:

	Ave.	σ_{n-1}	Max.	Min.
Fig. 11	16.95 Ω	8.73 Ω	28.14 Ω	4.80 Ω
Figs. 1 & 2	1.04 Ω	0.53 Ω	[0.70 Ω] <u>1.70Ω</u>	0.47 Ω

The paragraph on page 12, lines 3-16, has been rewritten as follows:

In the fifth embodiment, after placing the EMI shield member 11 in desired alignment over the electronic assembly, application of pressure brings each circular aperture defining contact wall 13 into contact with the cylindrical side surface of the second portion 50b of the

corresponding one of the contact protuberances 50. After completed, the second portions 50b of contact protuberances 50 close the circular apertures with their tops as high as the remote surface of the EMI shield member 11. Besides, the first portion 50a of each contact protuberance 50 allows the surface of the EMI shield member 11 to rest on the top thereof at around the associated second portion 50b. The cylindrical side surface of the second portion 50b of each contact protuberance [40] 50 is in contact with the corresponding one of the aperture defining contact walls 13.

IN THE CLAIMS

Claims 1, 3, 10, 12, 15, and 18 have been rewritten as follows:

1. (Once Amended) An EMI shielding structure, comprising:
 - a printed circuit having at least one contact protuberance; and
 - an EMI shield member formed with an aperture receiving the contact protuberance,
 - the EMI shield member having a contact wall defining the aperture, the aperture defining contact wall being in contact with the contact protuberance received in the [aperture.] aperture,
 - the contact protuberance being dimensioned such that the contact protuberance supports the EMI shield member.

3. (Once Amended) An EMI shielding structure, comprising:

a printed circuit having at least one contact protuberance; and

an EMI shield member formed with an aperture receiving the contact protuberance,

the EMI shield member having a contact wall defining the aperture, the aperture defining contact wall being in contact with the contact protuberance received in the aperture,

the contact protuberance having a vertex protruded through the aperture beyond the EMI shield [member.] member, the contact protuberance being dimensioned such that the contact protuberance supports the EMI shield member.

10. (Once Amended) An EMI shielding structure, comprising:

a printed circuit having at least one contact protuberance; and

an EMI shield member formed with an aperture receiving the contact protuberance,

the EMI shield member having a contact wall defining the aperture, the aperture defining contact wall being in contact with the contact protuberance received in the aperture,

the contact protuberance having a uniform cross sectional [area and] area, being fitted into the [aperture.] aperture, and being dimensioned such that the contact protuberance supports the EMI shield member.

12. (Once Amended) An EMI shielding structure, comprising:
- a printed circuit having at least one contact protuberance; and
- an EMI shield member formed with an aperture receiving the contact protuberance,
- the EMI shield member having a contact wall defining the aperture, the aperture defining contact wall being in contact with the contact protuberance received in the aperture,
- the contact protuberance having a first portion and an integral second portion fitted into the aperture,
- the second portion having a cross sectional area less than a cross sectional area of the first portion,
- the first portion allowing the EMI shield member to rest and be supported thereon.
15. (Once Amended) A method of assembling an EMI shielding structure, comprising:
- forming a printed circuit with at least one contact protuberance;
- forming an EMI shield member with an aperture and a contact wall defining the aperture;
- and
- placing the EMI shield member in a desired alignment over the printed circuit in a manner that the aperture receives the contact protuberance in contact with the aperture defining contact [wall.] wall and such that the contact protuberance supports the EMI shield member.

18. (Once Amended) An EMI shielding structure, comprising:

a ground [plane:] plane;

at least one contact protuberance on the ground plane; and

an EMI shield member formed with an aperture receiving the contact protuberance,

the EMI shield member having a contact wall defining the aperture, the aperture defining contact wall being in contact with the contact protuberance received in the [aperture.] aperture;

the contact protuberance being dimensioned such that the contact protuberance supports the EMI shield member.